



# Silicon Wafer Japan TC Chapter

Japan Standards Spring Meetings 2024

Friday, April 26, 2024

Official Virtual TC Chapter Meeting

10:00-12:00 JST

## AGENDA

### **1 Welcome/Call to Order**

- 1.1 Introductions
- 1.2 Required Elements (Membership Requirements, Antitrust and Intellectual Property Reminders, and Effective Meeting Guidelines)
- 1.3 Agenda Review

### **2 Review of Previous Meeting Minutes**

### **3 Liaison Report**

- 3.1 JRSC Report
- 3.2 GCS Report
- 3.3 Europe TC Chapter
- 3.4 North America TC Chapter

### **4 Staff Report**

### **5 Ballot Review**

None

### **6 Subcommittee & Task Force Reports**

- 6.1 International Advanced Wafer Geometry Task Force
- 6.2 International/ Japan Test Method Task Force
- 6.3 International Advanced Surface Inspection Task Force
- 6.4 International Polished Wafers Task Force
- 6.5 International Epitaxial Wafers Task Force
- 6.6 International Annealed Wafers Task Force



6.7 International SOI Wafers Task Force

6.8 International Terminology Task Force

**7 Old Business**

7.1 Project Period Review

7.2 5-year Review

- SEMI M88-0119, Practice for Sample Preparation Methods for Measuring Minority Carrier Diffusion Length in Silicon Wafers by Surface Photovoltage Methods
- SEMI M85-0120, Guide for the Measurement of Trace Metal Contamination on Silicon Wafer Surface by Inductively Coupled Plasma Mass Spectrometry

**8 New Business**

**9 Action Item Review**

9.1 Open Action Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
SW20231214-01	Test Method TF	To review the contents of SMI M88 to decide whether it is reapproval ballot by next TC Chapter meeting.
SW20231214-02	Tetsuya Nakai (SUMCO)	To inform the proposal and ask each TF leaders regarding M52 and M73 to proceed the action.

9.2 New Action Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>

**10 Next Meeting and Adjournment**

10.1 The next meeting is scheduled for <date> at <event/location>.